



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Florence Eschbach et al. Art Unit: 1773
Serial No.: 10/649,354 Examiner: Vivian Chen
Filed : August 26, 2003
Assignee : Intel Corporation
Title : ATTACHING A PELLICLE FRAME TO A RETICLE

MAIL STOP AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicants call attention to the attached Information Disclosure Statement and documents listed on form PTO-1449.

The documents are in the English language; hence no concise explanation is necessary per Rule 98(a)(3).

Consideration of the foregoing and enclosures plus the return of a copy of the enclosed form PTO-1449 with the Examiner's initials in the left column per MPEP 609 are earnestly solicited along with an early action on the merits.

08/09/2006 CNEGA1 00000014 061050 10649354
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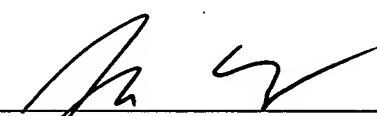
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Respectfully submitted,

Date: August 4, 2006

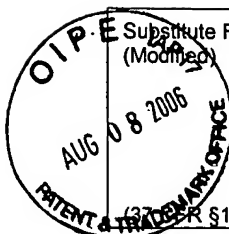


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 Substitute Form PTO-1449
(Modified)

 U.S. Department of Commerce
Patent and Trademark Office

 Attorney's Docket No.
10559-887001

 Application No.
10/649,354

**Information Disclosure Statement
by Applicant**

(Use several sheets if necessary)

 Applicant
Florence Eschbach et al.

 Filing Date
August 26, 2003

 Group Art Unit
1773

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	2003/0187168	10/2003	Sunaga et al.			
	AB	2005/0202252	09/2005	Tregub et al.			
	AC	2005/0203254	09/2005	Tregub et al.			
	AD	4,737,387	04/1988	Yen			
	AE	5,880,204	03/1999	McCarthy et al.			
	AF	6,111,062	08/2000	Shirota et al.			
	AG	6,548,129	04/2003	Matsukura et al.			
	AH	6,652,958	11/2003	Tobita			

Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AI	0 252 673	01/1988	Europe				
	AJ	0 416 528	03/1991	Europe				

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
	AK	Karis, et al., "Characterization of a solid fluorocarbon film on magnetic recording media", <i>J. Vac. Sci. Technol. A</i> , 15(4):2382-2387, (1997).
	AL	Karis, et al., "Tribology of a Solid Fluorocarbon Film on Magnetic Recording Media", <i>IEEE Transactions on Magnetism</i> , 34(4):1747-1749, (1998).
	AM	LaPedus, M., "Nikon evaluating 157-nm lithography options", <i>EE Times UK</i> , http://www.eetuk.com/tech/news/dev/OEG20030523S0061 , May 24, 2003.
	AN	Resnick & Buck, "Teflon® AF Amorphous Fluoropolymers", <i>Modern Fluoropolymers</i> , Edited by J. Schews, John Wiley & Sons, Inc., pp. 397-419, (1997).
	AO	Seki, et al., "Electronic Structure of Poly(tetrafluoroethylene) Studied by UPS, VUV Absorption, and Band Calculations", <i>Physica Scripta</i> , 41(1):167-171, (1990).
	AP	Singer, P., "Atomic Layer Deposition Targets Thin Films", <i>Semiconductor International</i> , 22(10):40, (1999).
	AQ	Sugiyama, "Perfluoropolymers Obtained by Cyclopolymerization and Their Applications", <i>Modern Fluoropolymers</i> , Edited by J. Schews, John Wiley & Sons, Inc., pp. 541-555, (1997).
	AR	Theirich, et al., "A novel technique for high rate plasma polymerization with radio frequency plasmas", <i>Surface and Coatings Technology</i> , 86-87, pp. 628-633, (1996).
	AS	Walton, K.R., "The Lubrication of Gold Surfaces by Plasma-Deposited Thin Films of Fluorocarbon Polymer," <i>IEEE Transactions on Components, Hybrids, and Manufacturing Technology</i> , CHMT-3(2):297-304, (1980).

Examiner Signature

Date Considered

EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.